

EV317136615



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

18/E
Inresa
8/18/03

Application Serial No.09/920,978
Filing Date August 1, 2001
Inventor Shane J. Trapp
Assignee Micron Technology, Inc.
Group Art Unit 2813
Examiner David S. Blum
Attorney's Docket No.MI22-1674
Title: Method of Forming Integrated Circuitry and Method of Forming Shallow
Trench Isolation in a Semiconductor Substrate

RESPONSE TO APRIL 29, 2003 OFFICE ACTION

To: Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

VIA EXPRESS MAIL

From: Mark S. Matkin (Tel. 509-624-4276; Fax 509-838-3424)
Wells St. John P.S.
601 West First Avenue, Suite 1300
Spokane, WA 99201-3828

Responsive to the Office Action dated April 29, 2003, Applicant amends
and remarks as follows:

CLAIMS

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JUL 30 2003
TECHNOLOGY CENTER 2800